

<b>Notice of References Cited</b>	Application/Control No. 09/052,688	Applicant(s)/Patent Under Reexamination CLEVENGER ET AL.	
	Examiner Ginette Peralta	Art Unit 2814	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
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**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Toyoda, H. et al.; "Improvement in the Electromigration Lifetime Using Hyper-Textured Aluminum Formed on Amorphous Tantalum-Aluminum Underlayer"; 32 <sup>nd</sup> Annual Proceedings Reliability Physics Symposium, 11-14 April, 1994. IEEE International, pp. 178-184
	V	
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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